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## BIB DATA SHEET

## CONFIRMATION NO. 7026

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
10/593,254	09/18/2006 RULE	427	1792	296428US26PCT

## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a 371 of PCT/JP05/06158 03/30/2005

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 2004-105300 03/31/2004

## \*\* IF REQUIRED, FOREIGN FILING LICENSE GRANTED \*\*

03/14/2007

Foreign Priority claimed	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	STATE OR COUNTRY	SHEETS DRAWINGS	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119(a-d) conditions met	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No				
Verified and /JOSEPH ALBERT MILLER, JR. Examiner's Signature	<input type="checkbox"/> Met after Allowance  Initials	JAPAN	9	16	3
Acknowledged					

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## TITLE

Method and apparatus for forming metal silicate film, and method for manufacturing semiconductor device

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